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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hiroiyuki ABE et al.

Application No.: 08/930,449

Filed: October 7, 1997

Group Art Unit: 2814

Examiner: S. Rao

Docket No.: 039514

#29H Suppl Andot  
M. Baunsm  
2/25/02

For: HIGH ENERGY SUPPLY APPARATUS, METHOD OF FORMING CRYSTALLINE FILM AND METHOD OF MANUFACTURING THIN FILM ELECTRONIC DEVICE

SUPPLEMENTAL AMENDMENT

Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

As a supplement to the Amendment filed on December 12, 2002, and in response to the January 9 and 14, 2003 telephone interviews, please further amend the above-identified application as follows:

IN THE CLAIMS:

Please replace claims 1, 12, 20, 25, 30, 35, 40, 46 and 56 as follows:

- Sub 1 ✓
1. (Seven Times Amended) A method of forming a crystalline film, comprising:  
forming a thin film having a surface on a glass substrate; and  
crystallizing at least a surface layer of the thin film by applying energy through a window that exhibits transparency to the energy to the surface of the thin film, wherein a distance between the window and the thin film is more than about 20 mm, and at least the surface layer of the thin film is melted by the applied energy and crystallized by cooling solidification under a hydrogen-containing atmosphere of at least atmospheric pressure,  
wherein unpaired bonding electrons on the surface of the thin film during the cooling solidification are terminated by hydrogen atoms in the hydrogen-containing atmosphere of at least atmospheric pressure.
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